

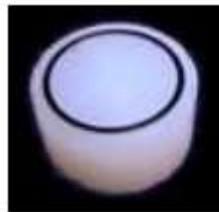


SPIN 200i Specifications

싱글프로세스용 스피너코터.

용도 :cleaning, drying, coating, developing
etching up to Ø260mm substrates:

- * 가능사이즈: up to Ø260mm wafer, 150mm x 150mm
- 재질 : Full 플라스틱 하우징(NPP) -옵션:테플론 가능
- T투명한 뚜껑및 중앙에 디스펜싱용 시린지홀더Hall
수동 디스펜싱및 오토디스펜싱 가능(옵션키트 필요)
- Automatic safety lid lock with sensor interlock
- Detachable controller interface for easy
integration :spin200i-ind 형(글로벌박스 설치시 유리)
- N₂ diffuser for N₂ purge during process
- Easy, step-by-step recipe programming via large
colour touchscreen
- Unlimited Program Storage for recipes with
multiple steps / each for:
 - Time 0.1-99999 sec/step
 - Speed 0-12,000 rpm
 - 회전방향 변경 가능 (CW, CCW, puddling)
 - Acceleration / Deceleration 1-30,000rpm/sec,
selectable per step
 - Vacuum On/Off
 - 3 Programmable Dry Contacts:
e.g. for automated control of Dispense unit,
Nitrogen diffuser, etc.
- Structured and password protected recipe
storage for easy and safe management
- 고정밀 독일제 DC서보 모터 장착 최고의 Coating Thickness Uniformaty 실현 가능



A-V36-S45-PP



D-V10-S50-PP
on A-V36-S45-PP

Standard included:

- (1) standard Vacuum Chuck A-V87-S96-PP-HD Ø96mm for up to Ø8" wafers.or A-V36-S45-PP-HD for 6"
- (1) D-V10-S50-PP, Small Fragment Adapter
(for Ø ½"- Ø 2" Pieces and Fragments optional) (Alternative chucks optionally available)
- Drain connection 1" male NPT (Exhaust Hose optionally available)



Tel. 031-479-4211/2

jsi@jsits.com

sps-korea.com



SPIN150i Specifications

Performance:

Available number of programs:	Unlimited*
Steps per program:	Unlimited*
Spin speed:*	1 – 12,000 rpm** ± 1rpm steps
Spin speed accuracy:	± 0.1 rpm **
Spin rotational direction:	Clockwise, Counter clockwise, Puddle
Max. acceleration:	30,000 rpm/sec**
Spin time	Unlimited*, ± 0.1 seconds steps
Free programmable outputs:	3 pcs, relays, nominal switching capacity 0,5 A/125 VAC – 0.3A/60VDC

System data:

Housing material:	Natural Polypropylene (NPP)***
Process chamber material:	Natural Polypropylene (NPP)***
Interface:	Detachable, full-size touchscreen, glove-friendly, IP52, chemical resistant
External connection:	1 USB Port in the controller
Max. substrate diameter:	160 mm (or 4"x4" square)
Max. process chamber diameter:	202 mm
Dimension (desktop version):	274 (w) x 250 (h) x 451 (d) mm
Shipping weight:	14 kgs
Shipping dimension:	600 x 380 x 360 mm

Requirements

Voltage:	100 - 120 VAC / 200 - 240 VAC 50/60 Hz (auto select)
Power consumption:	Max. 500 W
Max. current:	5A / 2,5A
Vacuum:	-65 kPa (-19 inchHg), ≥ 80 lpm tube OD Ø8mm
Motor purge gas:	20 - 50 kPa, 2-5 l/min, Tube OD Ø 6mm
Drain connection:	1" M-NPT

* Considering additional capability of standard unit such as USB backup, recipe cycling, PC software etc.

** Measured without substrate, limitations may apply depending on chuck used and substrate specification.

*** For our spin processors and chucks we use **NPP-H** with α -crystalline properties.

www.sps-korea.com



Tel. 031-479-4211/2

jsi@jsits.com